



Wearable and Implantable Bio-MEMS Devices and Applications

Guest Editor:

Dr. Bowen Ji

Unmanned System Research
Institute, Northwestern
Polytechnical University, Xi'an
710072, China

Deadline for manuscript
submissions:

closed (31 December 2023)

Message from the Guest Editor

Wearable and implantable MEMS sensors and actuators have attracted tremendous attention in health monitoring, disease treatment, human-machine interaction, etc. due to their flexibility, minimization, low power consumption, and biocompatibility. This Special Issue focuses on the recent development and solution of wearable and implantable bio-MEMS devices from the aspects of optimized design methods, micromachining technology, and microsystem integration on any potential application. Wearable and implantable bio- and medical MEMS devices are expected to revolutionize personalized healthcare monitoring and precision therapy, and thus, continued efforts to develop wearable and implantable devices and systems hold great promise for the quality of people's lives. Any other topics related to bio- and medical MEMS are also welcome.





an Open Access Journal by MDPI

Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (*Physics, Applied*) / CiteScore - Q2 (*Mechanical Engineering*)

Contact Us

Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://twitter.com/micromach_mdpi)